Micropatterning Japan TC
Meeting Summary and Minutes

SEMI Japan Standards Summer 2015 Meetings
Thursday, January 28, 2016, 15:30-17:30
SEMI Japan, Tokyo, Japan

Next Committee Meeting
SEMI Japan Standards Spring 2016 Meetings
Thursday, May 12, 2016, 15:30-17:30
SEMI Japan, Tokyo, Japan

Table 1 Meeting Attendees
Co-Chairs: Morihisa Hoga (Dai Nippon Printing)
SEMI Staff: Junko Collins (SEMI Japan)

<table>
<thead>
<tr>
<th>Company</th>
<th>Last</th>
<th>First</th>
<th>Company</th>
<th>Last</th>
<th>First</th>
</tr>
</thead>
<tbody>
<tr>
<td>Dai Nippon Printing</td>
<td>Hoga</td>
<td>Morihisa</td>
<td>Dai Nippon Printing</td>
<td>Suzuki</td>
<td>Toshio</td>
</tr>
<tr>
<td>-</td>
<td>Otaki</td>
<td>Masao</td>
<td>SEMI Japan</td>
<td>Collins</td>
<td>Junko</td>
</tr>
</tbody>
</table>

Table 2 Leadership Changes
None

Table 3 Ballot Results
Doc. #5229B, Revision to SEMI P44-0211, Specification for Open Artwork System interchange Standard (OASIS®) Specific to Mask Tools Passed as balloted

Table 4 Authorized Ballots

<table>
<thead>
<tr>
<th>#</th>
<th>When</th>
<th>SC/TF/WG</th>
<th>Details</th>
</tr>
</thead>
<tbody>
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None

Table 5 Authorized Activities

<table>
<thead>
<tr>
<th>#</th>
<th>Type</th>
<th>SC/TF/WG</th>
<th>Details</th>
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None
### Table 6 New Action Items

<table>
<thead>
<tr>
<th>Item #</th>
<th>Assigned to</th>
<th>Details</th>
</tr>
</thead>
<tbody>
<tr>
<td>MP160128-1</td>
<td>Junko Collins</td>
<td>To submit Ballot Report of 5229B to A&amp;R in a timely manner</td>
</tr>
<tr>
<td>MP160128-2</td>
<td>Junko Collins</td>
<td>To ask responsible staff schedule of publication regarding 5229B</td>
</tr>
</tbody>
</table>
| MP160128-3 | Junko Collins | To inform Japan TC Chapter members that disbandment of Japan TC Chapter will be motioned at the next TC Chapter meeting.  
To include above information in the liaison report to NA. |
| MP160128-4 | Morihisa Hoga | To communicate with NA Chairs about the document status and ownership    |
1 Welcome, Reminders and Introductions
Morihisa Hoga, committee co-chair, called the meeting to order at 15:30. Self-introductions were made followed by the agenda review.

2 Required Meeting Elements
The meeting reminders on program membership requirement, antitrust issues, intellectual property issues and international effective meeting guidelines, were reviewed by SEMI staff, Junko Collins.

Attachment: Required_Elements_Reg_20150327_E+J

3 Review of Previous Meeting Minutes
The committee reviewed the minutes of the previous meeting held on October 15, 2015.

Motion: To approve the minutes of the previous meeting with some editorial changes.
By / 2nd: Toshio Suzuki (Dainippon Printing) / Masako Otaki (-)
Discussion: None
Vote: 2 in favor and 0 opposed. Motion passed.

4 SEMI Staff Report
Junko Collins gave the SEMI staff report. This report included SEMI Global Calendar of Events, Global Standards Meeting Schedule, Critical Dates for SEMI Standards Ballots, SEMI Standards Publication and Contact Information.

Attachment: 4.0_SEMI Staff Report 20151215_r1(MP)

5 Liaison Reports
5.1 Microlithography North America TC Report
Participants reviewed the meeting minutes during SEMCON West 2015.
Next meeting is scheduled on February 24 in conjunction with SPIE Advanced Lithography Conference at San Jose, California.

Attachment: 5.0_NA Micro Report Jan 2016

6 Ballot Review
6.1 Doc. #5229B, Revision to SEMI P44-0211, Specification for Open Artwork System interchange Standard (OASIS®) Specific to Mask Tools

Attachment: 5229B Ballot report

7 Task Force Reports
7.1 Mask Data Format for Mask Tools Task Force
Toshio Suzuki reported for the Mask data Format for Mask Tools Task Force. Of note:
- Doc. #5229B, Revision to SEMI P44-0211, Specification for Open Artwork System interchange Standard (OASIS®) Specific to Mask Tools, passed as balloted.
Staff will forward the report to A&R with timely manner and ask responsible staff about schedule for publication.

Inactive status of P45 was discussed at this meeting and it has been included in the list currently drafted by M. Hoga.

7.2 5 Year Review Task Force
Masao Otaki reported on progress for the 5 Year Review Task Force, but no special report for this time.

8 Old Business

8.1 Previous Meeting Action Items
Junko Collins reviewed the previous meeting action items.

Table 7 Previous Meeting Actions Items

<table>
<thead>
<tr>
<th>Item #</th>
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<th>Details</th>
</tr>
</thead>
<tbody>
<tr>
<td>MP121015-1</td>
<td>Toshio Suzuki</td>
<td>To submit 5229B to Cycle 8 → Closed</td>
</tr>
<tr>
<td>MP121015-2</td>
<td>Morihisa Hoga</td>
<td>To complete the document list to identify which document should be inactive status with respect to the document which were originated by Japan TC Chapter → Closed</td>
</tr>
<tr>
<td>MP121015-3</td>
<td>Toshio Suzuki</td>
<td>To communicate with stakeholders who requested the SNARF 5366: Revision to P45, about “inactive” status for P45. → Closed</td>
</tr>
</tbody>
</table>

8.2 Disbandment of this TC chapter
M. Hoga reported the current situation of this TC chapter. See the details in the attachment.

At the inception of disbanding the TC Chapter, members identify the documents originated by this TC Chapter and all those documents were decided to be inactive status. See the attachment.

Motion: To approve the documents in the attachment “Japan MP TC Chapter_160127 R0.1” should be inactive status when this TC Chapter is disbanded.

By / 2nd: Masako Otaki (-) / Toshio Suzuki (Dainippon Printing)

Discussion: This list should be reported at the NA Microlithography (NA Micropattering TC Chapter) meeting for double checking. If NA TC Chapter wants to keep ownership of some documents, these documents should be removed from this list.

Vote: 2 in favor and 0 opposed. Motion passed.

At the next meeting, disbanding Japan TC Chapter will be motioned at the next TC Chapter meeting. Before that, staff announces it to Japan TC Chapter members. Also this information will be included in the liaison report to NA TC Chapter.

Attachment: Japan MP TC Chapter_160127 R0.1

9 New Business
None

10 Action Item Review

10.1 New Action Items
Junko Collins reviewed the new action items. These can be found in the New Action Items table at the beginning of these minutes.
11 Next Meeting and Adjournment

The next meeting of the Micropatterning Japan TC meeting is scheduled for Thursday, January 28, 2016, 15:30-18:00, at SEMI Japan, Tokyo, Japan.
Respectfully submitted by:
Junko Collins
Director, Standards & EHS
SEMI Japan
Phone: +81.3.3222.5819
Email: jcollins@semi.org

Minutes approved by:

| Morihisa Hoga (Dai Nippon Printing), Co-chair | MH |

**Table 8 Index of Available Attachments #1**

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<thead>
<tr>
<th>Title</th>
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#1 Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at www.semi.org. For additional information or to obtain individual attachments, please contact Junko Collins at the contact information above.